

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Junji NOGUCHI et al.

Appln. No.:

Filed: Herewith

For: SEMICONDUCTOR DEVICE AND MANUFACTURING  
METHOD THEREOF

\* \* \*

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.56, and without any  
assertion as to materiality or prior art effect, the  
documents listed on the attached Form PTO-1449 are hereby  
cited.

Documents AQ and BJ-BK listed on the attached List are  
cited in the specification, on pages 1-2, and their  
relevance is indicated therein.

Documents AA-AH and BA-BB are U.S. counterparts of  
Documents AI-AP and BI-BJ, respectively.

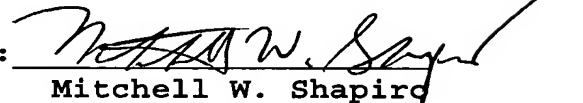
Respectfully submitted,

MWS:sjk

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March 24, 2004

By:



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Reg. No. 31,568

FORM PTO-1449				Atty. Docket No. XA-10063		Appln. No.	
<u>LIST OF DOCUMENTS CITED BY APPLICANT</u>				Applicant Junji NOGUCHI et al.			
				Filing Date Herewith		Group	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub- class	Filing Date
	AA	6,555,464	04/29/03	Fukada et al.	438	622	
	AB	2002/0127843	09/12/02	Noguchi et al.	438	622	
	AC	2001/0045651	11/29/01	Saito et al.	257	750	
	AD	2001/0030367	10/18/01	Noguchi et al.	257	758	
	AE	2002/0042193	04/11/02	Noguchi et al.	438	618	
	AF	2002/0100984	08/01/02	Oshima et al.	257	774	
	AG	2003/0030146	02/13/03	Tamaru et al.	257	762	
	AH	2003/0087513	05/08/03	Noguchi et al.	438	627	
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub- class	Translation
	AI	2000-349150	12/15/00	Japan			Abstract
	AJ	2001-53076	02/23/01	Japan			Abstract
	AK	2001-319928	11/16/01	Japan			Abstract
	AL	2001-291720	10/19/01	Japan			Abstract
	AM	2002-110679	04/12/02	Japan			Abstract
	AN	2002-164428	06/07/02	Japan			Abstract
	AO	2003-60030	02/28/03	Japan			Abstract
	AP	2003-142579	05/16/03	Japan			Abstract
OTHER (including author, title, date, pertinent pages, etc.)							
	AQ	Chiang et al., "TDDB Reliability Improvement in Cu Damascene by using a Bilayer-Structured PECVC SiC Dielectric Barrier", IEEE 2002 International Interconnect Technology Conference, June 3-5, 2002, pp. 200-202.					
Examiner				Date Considered			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							

<b>FORM PTO-1449</b>				<b>Atty. Docket No.</b> XA-10063		<b>Appln. No.</b>	
<b><u>LIST OF DOCUMENTS CITED BY APPLICANT</u></b>				<b>Applicant</b> Junji NOGUCHI et al.			
				<b>Filing Date</b> Herewith		<b>Group</b>	
<b>U.S. PATENT DOCUMENTS</b>							
<b>Examiner Initial</b>		<b>Document Number</b>	<b>Date</b>	<b>Name</b>	<b>Class</b>	<b>Sub-class</b>	<b>Filing Date</b>
	BA	2003/0183940	10/02/03	Noguchi et al.	257	767	
	BB	6,514,852	02/04/03	Usami	438	624	
	BC						
	BD						
	BE						
	BF						
	BG						
	BH						
<b>FOREIGN PATENT DOCUMENTS</b>							
<b>Examiner Initial</b>		<b>Document Number</b>	<b>Date</b>	<b>Country</b>	<b>Class</b>	<b>Sub-class</b>	<b>Translation</b>
	BI	2003-297918	10/17/03	Japan			Abstract
	BJ	2002-43419	02/08/02	Japan			Abstract
	BK	2002-270691	09/20/02	Japan			Abstract
	BL						
	BM						
	BN						
	BO						
	BP						
<b>OTHER (including author, title, date, pertinent pages, etc.)</b>							
	BQ						
<b>Examiner</b>				<b>Date Considered</b>			
<b>EXAMINER:</b> Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							